

Figure 1. Representative AFM line scans of (A) pre-CMP silicon wafer and (B) silicon wafer after 3000 Al₂O₃ ALD cycles.

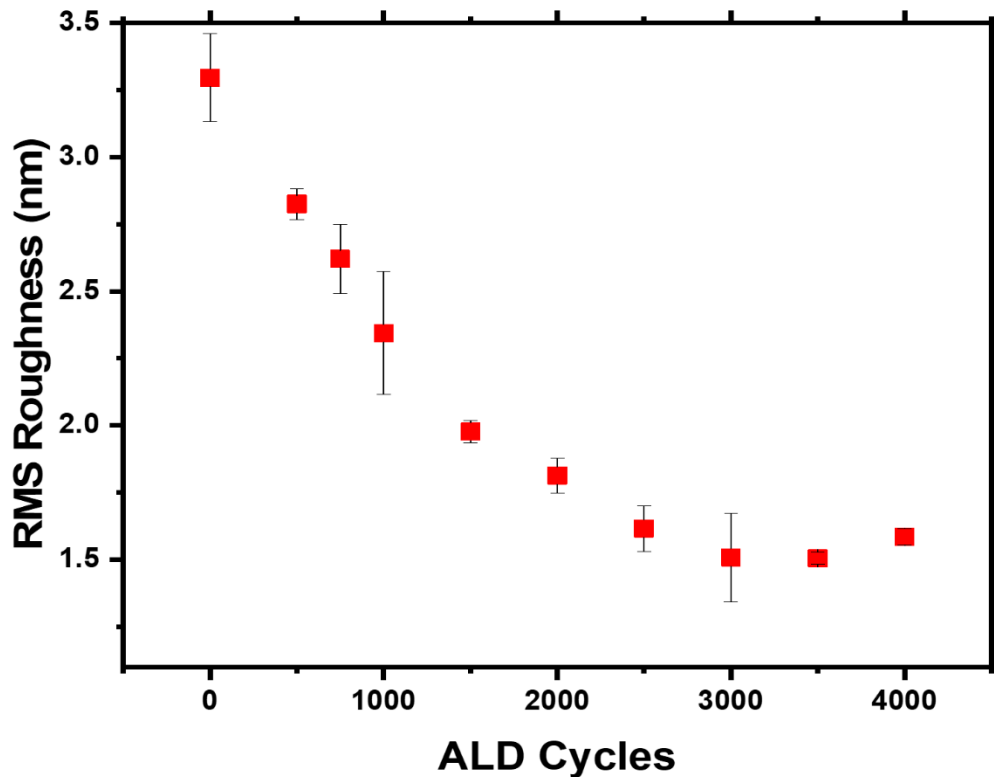


Figure 2. RMS roughness versus number of Al₂O₃ ALD cycles for an initial rough, pre-CMP silicon wafer.